



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

ATTY.'S DOCKET: NREL/96-48

#21/100  
12/14/00  
V. Vannal

Applicant: Timothy A. Gessert )  
Serial No.: 08/937,721 ) Group Art: 1741  
Filing Date: September 25, 1997 ) Examiner: S. Mulpuri  
Title: ION-BEAM TREATMENT TO )  
PREPARE SURFACES OF )  
P-CdTe FILMS )

*Please enter  
after final  
and  
for 12/14/00*

AMENDMENT UNDER 37 C.F.R. § 1.116

Honorable Commissioner of Patents and Trademarks  
Washington, D.C. 20231

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Sir:

In reply to the Official Action of November 11, 2000, which rejected the claims in the above-identified patent application, applicant respectfully request reconsideration, based upon the amendments hereinafter set forth.

IN THE CLAIMS:

Please cancel claims 2 and 3 without prejudice.

1. (Twice Amended) A dry process for making a low-resistance uniform and reproducible surface for electrical contact between a metal and a layer of polycrystalline p-type CdTe surface by ion beam processing comprising:

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21

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